

## PATENT



**IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE**

Applicant: Geun Su Lee et al.

Serial No.: 10/723,029

Filed: November 26, 2003

**Title: Cleaning Solution for Photoresist and Method for Forming Pattern Using the Same**

Group Art Unit: 1756

Examiner: Not yet assigned

I hereby certify that this paper (or fee) is being deposited with the United States Postal Service, first class postage prepaid, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

March 28, 2006

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## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**Sir:**

The documents listed on the enclosed Form PTO-1449 are identified pursuant to 37 CFR §§ 1.56, 1.97, and 1.98. Copies of the documents are enclosed as required.

The documents were cited in an official action (copy submitted herewith) dated December 28, 2005, during the prosecution of counterpart Korean Patent Application No. 2003-14796.

Entry and consideration of the submitted documents are solicited.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

March 28, 2006

By: 

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<b>INFORMATION DISCLOSURE STATEMENT</b>	USPTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. <b>30205/39714</b>	Serial No. <b>10/723,029</b>
	Applicant <b>Geun Su Lee</b>			
	Filing Date <b>11/26/2003</b>		Group <b>1756</b>	

U.S. PATENT DOCUMENTS							
*Examiner Initials		Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate
		3,953,386	04/27/76	Murphy et al	260	17	
		5,196,070	03/23/93	Ables et al	148	23	

FOREIGN PATENT DOCUMENTS								
*Examiner Initials		Document Number	Publication Date	Country	Class	Subclass	Translation	
							Yes	No
		04-124668	04/24/92	Japan			Abstract only	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
		Office action in corresponding Korean Application No. 2003-14796 dated December 28, 2005

Examiner	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	